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(54) Title: ELECTROSTATIC TRAY AND BASE

(54) 发明名称: 静电托盘及基座

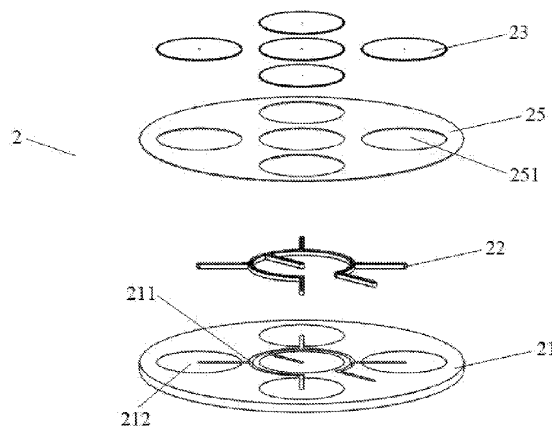


图 1

(57) Abstract: Provided in the present invention are an electrostatic tray and a base. The electrostatic tray comprises a tray body, a voltage feed-in component and a plurality of adhesion components, wherein the plurality of adhesion components are arranged on the tray body at intervals, and each adhesion component comprises an insulating layer, an electrode layer and a dielectric layer, which are sequentially arranged in a direction away from the tray body; and the voltage feed-in component is arranged between the adhesion components and the tray body and electrically connected to the electrode layers in the plurality of adhesion components, and the voltage feed-in component is used to feed direct-current voltage to the electrode layer of each adhesion component, so that a plurality of wafers are adhered by means of the plurality of adhesion components correspondingly on a one-to-one basis. By means of the electrostatic tray and the base provided in the present invention, the processing difficulty and cost of multi-piece electrostatic trays can be reduced, and

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the radio frequency coupling efficiency can be improved, thereby improving the semiconductor process efficiency.

(57) 摘要: 本发明提供一种静电托盘及基座, 其中, 静电托盘包括托盘本体、电压馈入部件和多个吸附部件, 多个吸附部件间隔设置于托盘本体上, 每个吸附部件均包括沿远离托盘本体的方向依次设置的绝缘层、电极层和介电层; 电压馈入部件设置在吸附部件与托盘本体之间, 并与多个吸附部件中的电极层电连接, 电压馈入部件用于向每个吸附部件的电极层馈入直流电压, 以通过多个吸附部件一一对应的吸附多个晶圆。本发明提供的静电托盘及基座能够降低多片静电托盘的加工难度及成本, 并能够提高射频耦合效率, 提高半导体工艺效率。